

# APPLICATION DATA SHEET

Electronic Version 0.0.11

Stylesheet Version: 1.0

Attorney Docket Number: 740756-2680

Publication Filing Type: new-utility

Application Type: utility

Title of Invention: PLASMA TREATMENT APPARATUS AND METHOD FOR PLASMA TREATMENT

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Foreign Priority:

2002-358782

JP 2002-12-10

Priority Claimed

Assignee (Publish): Semiconductor Energy Laboratory Co., Ltd.

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